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Substitute for form 1449A/PTO

## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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	Complete if Known	
Application Number	10/849,348	
Filing Date	May 19, 2004	
First Named Inventor	Robert H. Burgener, II	
Group Art Unit	2814	
Examiner Name	Wai Sing Louie	
Attorney Docket Number	3398.2.10	

	U.S. PATENT DOCUMENTS				
Examiner		Document Number	Publication Date	Name of Patentee or Applicant of	Pages, Columns, Lines, Where Relevant
Initials *	Cite No.1	Number - Kind Code <sup>2 (F ARCAPA)</sup>	MM-DD-YYYY	Cited Document	Passages or Relevant Figures Appear
482	U1	US-2004/0061114 A1	04/01/2004	Yan et al.	
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	FOREIGN PATENT DOCUMENTS					
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Examiner Name	Wai Sing Louie			
Attorney Docket Number	3398.2.10			

		NON PATENT LITERATURE DOCUMENTS	
Examiner Initials *	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T?
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wsr	O15	WILKINSON, J., XIONG, G., UCER, K.B., and WILLIAMS, R.T.; Lifetime and Oscillator Strength of Excitonic Luminescence in Zinc Oxide; Department of Physics, Wake Forest University, Winston-Salem, NC.	
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Examiner Signature	The same	Date Considered	5/21/06

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WSV	O30	KOSSANYI, J., KOUYATE, D., POULIQUEN, J., RONFARD-HARET, J.C., VALAT, P., et al.; Photoluminescence of Semiconducting Zinc Oxide Containing Rare Earth lons as Impurities; Journal of Luminescence; 1990; pp. 17-24; Vol. 46; Elsevier Science Publishers B.V. (north-Holland).	3
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WSL	O46	ARKLES, B.; Commercial Applications of Sol-Gel-Derived Hybrid Materials; MRS Bulletin; 05/2001; pp. 402-407.	
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Substitute for form 1449B/PTO Complete if Known **Application Number** 10/849,348 INFORMATION DISCLOSURE May 19, 2004 Filing Date STATEMENT BY APPLICANT First Named Inventor Robert H. Burgener, II Group Art Unit (use as many sheets as necessary) Examiner Name Wai Sing Louie Attorney Docket Number 3398.2.10 Sheet Of

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				Application Number	10/849,348	
INF	ORMATIC	ON DISC	CLOSURE	Filing Date	May 19, 2004	
STA	ATEMENT	BY AP	PLICANT	First Named Inventor	Robert H. Burgener, II	
				Group Art Unit	2814	
	(use as many	sheets as ne	cessary)	Examiner Name	Wai Sing Louie	
Sheet	7	Of	9	Attorney Docket Number	3398.2.10	

wsi	O94	SENGER, R.T., and BAJAI, K.K.; Binding energies of excitons in polar quantum well heterostructures; Physical Review B; 2003; pp. 205314-1 -205314-9; Vol. 68; The American Physical Society.	١
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is		LEE, J-M., KIM, K.K., PARK, S-J., and CHOI, W.K.; Low-resistance and non-alloyed ohmic contacts to plasma treated ZnO; Applied Physics Letters; 06/11/2001; pp. 3842-2844; Vol. 78, No. 24; American Institute of Physics.	•
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